

**Amendments to the Specification**

**Please replace the paragraph beginning at page 24, line 4, with the following  
rewritten paragraph:**

As SAW element 55, piezoelectric substrate 51 having piezoelectricity such as a lithium tantalate (LiTaO<sub>3</sub>) single crystal substrate, a lithium niobate (LiNbO<sub>3</sub>) single crystal substrate, and a crystal substrate is used. An electrode thin film mainly including aluminum (Al) is formed on a surface of piezoelectric substrate 51 and a prescribed pattern shape is formed by performing a photolithography process and an etching process. SAW element 55 includes transmission filter 52 as a first surface acoustic wave filter structure, reception filter 53 as a second surface acoustic wave filter structure and shield electrode 54 having a grating shape, which is formed between transmission filter 52 and reception filter 53.